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FemtoLEED DLD L1000 Configuration Guide and Specifications



LEED configuration

Base configuration				
Model	Order Code			
DLD L1000		Femto-LEED optics for low energy electron beam application, with 3 grid high resolution retarding field analyzer, integral miniature electron gun, two 80 mm O.D. Long Life (TM) microchannel plates in chevron configuration with Au plating enhanced for pulsed mode, delay-line-hex-anode, Mu-metal shield mounted on the CF10" (DN200CF) O.D. flange.		
LMX		Integral linear retraction based on 4 linear ball bearings up to 100 mm		
LPS075-D		Digital power supply (0-750 V) with USB interface and PC control software for Windows 10. True primary beam current and total emission measurements. Automatic start-up and shut down, 10 memory settings including standby and outgassing mode with timer, constant beam current mode controlled by filament current or Wehnelt voltage. All cables included.		
MCPS2		Electronics for two microchannel plates with digital displays of voltages and MCP load current measurements and protection.		
Options				
ISH		Integral shutter		
LaB ₆		LaB ₆ single crystal filament instead of a tungsten wire filament		
DLA-TR8		Controller for delay line detector and computer interface PCI card		

LEED Software

Software Options				
Model	Order			
	Code			
LIM-DLD		LEED pattern measurements, analysis software & hardware for Windows 10 including:		
		- Automatic LEED pattern acquisition		



- Automatic I-V analysis with spot tracking - Automatic I-T analysis
- Automatic spot profile analysis

Detailed Specifications

Detailed Specifications				
FemtoLEED DLD L1000 op				
Detector	Delay Line Detector with dynamic range 32 bit per channel, 75 microns spatial resolution and active area diameter 75mm			
Angle of acceptance	77° from sample			
Retarding Field Analyzer	Concentric assembly of hemispherical grids			
Working distance from sample	15 mm			
Grid material	Gold coated tungsten wire mesh (100 mesh, 81% transparency)			
Energy resolution	0.2%			
Monitoring	10" standard viewport			
Linear motion	External nipple with bellow up to 150 mm retraction			
Integral shutter	Manual shutter driven by a rotary feedthrough			
Magnetic shielding	Mu metal cylinder with front cover for maximum attenuation			
Assembly	Extreme high vacuum compatibility with stainless steel, high alumina and			
	Au-plated copper alloy materials			
Mounting	CF10"(DN200CF) double sided conflat flange with sample distance 145 mm			
5 1 122	580 mm			
Bakeability	Under vacuum, 250°C maximum			
Integral miniature electro				
Beam energy	LEED: 0-750 eV			
Beam current	LEED: 2 μA at 100 eV and 0.5 mm beam size			
Beam size	From 1 mm to 250 μm-adjusted by wehnelt potential, limited by			
	exchangeable aperture down to 50 μm			
Electron source	Tungsten 2% thoriated filament (standard) or single crystal Laß filament (optional)			
Energy spread	0.45 eV (thoriated-tungsten filament)			
Overall size	10 mm lens diameter and 80 mm length			
Microchannel Plates	10 mm lens diameter and 00 mm length			
Working area	75 mm			
L/D ratio	80:1			
Channel diameter	13 microns			
Center to center spacing	32 microns			
Plate thickness	1.0 mm			
Bias angle	20°			
Electron gain	10 ⁷ , operating in pulsed mode			
LPS075-D Electronics	10 , operating in paised mode			
Beam Voltage	LPS075-D: negative 0-750 V			
Filament current	0-3.2 A Tungsten/ 0-2.1 A LaB			
Wehnelt voltage	0-3.2 A Tungsten, 0-2.1 A Lab			
Focus voltage	LEED: positive 70-180% of the beam voltage			
Retarding (grid) voltage	Negative 50-110% of the beam voltage			
Screen voltage	Positive 0-5000 V			
Emission current				
Beam current	1-200 μA			
	0.01-200 µA			
Monitoring	All voltages and currents Vacuum fluorescent, displaying all voltages, currents and program			
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Display	functions			
On-board automation	functions 5 pre-programmed and fully programmable operating programs for			
	functions 5 pre-programmed and fully programmable operating programs for outgassing, stand-by, filament forming, beam voltage scanning, constant			
On-board automation	functions 5 pre-programmed and fully programmable operating programs for outgassing, stand-by, filament forming, beam voltage scanning, constant beam current and diagnostics			
On-board automation Manual control	functions 5 pre-programmed and fully programmable operating programs for outgassing, stand-by, filament forming, beam voltage scanning, constant beam current and diagnostics Of all voltages via rotary dials and selection switches			
On-board automation	functions 5 pre-programmed and fully programmable operating programs for outgassing, stand-by, filament forming, beam voltage scanning, constant beam current and diagnostics			

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MCPS2 Electronics	
MCP Voltage	1 kV max per microchannel plate
Display	Vacuum florescent display
Manual Control	Of all voltages via rotary dials and selection switches
Protection	Over-voltage, over-current and short circuit protection
Mechanical	19" rack mount box with 2U (3.5", 90 mm) in height and 13.5" (350 mm) in depth. Weight: 6 kg

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